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28/2 #7/IOS DKung 10/31/81

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Signature: Reluced A. Boumarer

RECEIVED TO PATENT Attorney Docket No. NTI-019-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application)	PATENT APPLICATION
Inventor(s): Christophe Pierrat et al.)	
mivemor(s). Christophie Flerrat et al.	<i>)</i>	Art Unit: 2812
Application No.: 09/675,197)	.
Filed: 09/29/2000))	Examiner: unknown
)	
Title "Dissection Of Edges With Projection Points In A)	
Fabrication Layout For Correcting Proximity)	
Effects)	
)	

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

Listed below or one an attached Form PTO-1449 is information known to applicant(s). A copy of each listed publication and U.S. and foreign patent, except for pending U.S. applications, is being submitted herewith, along with a concise explanation of information in a foreign language, if any, pursuant to 37 C.F.R. §1.97-1.98.

Applicants respectfully request that the listed information be considered by the Examiner and be made of record in the above-identified application. If form PTO-1449 is enclosed, the Examiner is requested to initial and return it in accordance with MPEP § 609.

This statement is not intended to represent that a search has been made or that the information cited in the statement is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56.

\boxtimes	This statement qualifies under 37 C.F.R. § 1.97, subsection (b) because (check all that apply):					
		(1)	•	as of the application filing date and is other than a application under § 1.53(d)		
		(2)	It is being filed within 3 month	ns of entry of a national stage		
	\boxtimes	(3)		date of the first Office Action on the merits.		
		(4)		ling of a first Office Action after the filing of a request for under § 1.114		
	mailing	g date of		iled after the period specified in § 1.97(b), but before the on under § 1.113, a notice of allowance under § 1.311, or the application, then:		
		a certif	fication as specified in § 1.97(e)	is provided below; or		
			f \$180.00 as set forth in § 1.17(pnt of other papers filed together	b) is authorized below, enclosed, or included with the with this statement.		
37 C.F.R. § 1.97(d). If this statement is being filed after the period specified in § 1.97(c), but on o payment of the issue fee, then:						
	A.	a certif	fication as specified in § 1.97(e)	is completed below; and		
	B.		f \$180.00 as set forth in § 1.17(pnt of other papers filed together	b) is authorized below, enclosed, or included with the with this statement.		
	and ch	arge any		y authorized to charge the above-referenced fees of \$ 180 erpayment associated with this communication to Deposit .		
				Respectfully submitted,		
				BEVER, HOFFMAN & HARMS, LLP		
Dated:	_10	- [[- 0/	By:		
	·			Jeanette S. Harms, Reg. No. 35,537		
	one: (40 ier No.)8) 451-: 29477	5907			

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OF 15 2001 PTO-1449

ATTY. DOCKET NO.

SERIAL NO.

NTI-019-2

09/675,197

APPLICANT Pierrat, et al.

	·		FILING DATE 9/29/00		GR	OUP 2812	
Te TRADEMARK		U.S.	PATENT DOCUMENTS				
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CL	ASS	SUBCLASS	FILING DATI
	4,231,811	11/4/80	Somekh, et al.	1	48	1.5	9/13/79
	4,456,371	6/26/84	Lin	3	55	71	6/30/82
	4,902,899	2/20/90	Lin, et al.	2	50	492.1	6/1/87
	5,498,579	3/12/96	Borodovsky, et al.	4	37	250	6/8/94
	5,553,274	9/3/96	Liebmann	3	95	500	6/6/95
	5,636,002	6/3/97	Garofalo	3	55	53	10/31/95
	5,663,017	9/2/97	Schinella, et al.	4	30	5	6/7/95
	5,663,893	9/2/97	Wampler et al.	3	64	491	5/3/95
	5,723,233	3/3/98	Garza, et al.	4	30	5	2/27/96
	5,766,806	6/16/98	Spence	4	30	5	9/9/96
	5,821,014	10/13/98	Chen, et al.	4	30	5	2/28/97
	5,862,058	1/19/99	Samuels, et al.	3	64	491	5/16/96
	5,879,844	3/9/99	Yamamoto, et al.	4	30	30	12/20/96
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	5,900,338	5/4/99	Garza, et al.	4	30	5	8/15/97
	5,994,002	11/30/99	Matsuoka	4	30	5	9/4/97
	6,004,702	12/21/99	Lin	4	30	5	5/21/98
	6,077,310	6/20/00	Yamamoto, et al.	7	16	19	1/29/99
	6,078,738	6/20/00	Garza, et al.	3	95	500.22	5/8/97
<u></u>							
XAMINER			DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



INFORMATION DISCLOSURE		ATTY. DOCKET NO.	į		RIAL NO.				
		NTI-019-2 09/675,197							
1 5 2001	1910-1449		APPLICANT Pierrat, et al.						
			FILING DATE 9/29/00 GROUP 2812						
FEBRUA IRADEMA		FOR	EIGN PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLA	CLASS SUBCLASS		TRANS	LATION	
INITIALS							YES	NO	
	3-210560	9/13/91	JР						
	8-236317	9/6/96	JP						
	10-133356	5/22/98	JP						
1	11-143085	5/28/99	JP						
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EXAMINER		•	DATE CONSIDERED						

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INFORMA	ΓΙΟΝ DISCLOSURE	ATTY. DOCKET NO.	SERIAL NO.			
1	CITATION	NTI-019-2	09/675,197			
OTP E 70, TO-1449		APPLICANT Pierrat, et al.				
OCT 15 2001		FILING DATE 9/29/00	GROUP 2812			
The way	OTHER DOCUMENTS (Including Author, Title, Date, Perti	nent Pages, Etc.)			
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		Asai, N. et al., "Proposal For The Coma Aberration Dependent Overlay Error Compensation Technology", Ipn. J. Appl. Phys., Vol. 37, pp. 6718-6722 (1998).				
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	Garofalo, J. et al., "Mask Assisted Off-Axis Illumination Technique For Random Logic", J. Vac. Sci. Technol. B, Vol. 11, No. 6, pp. 2651-2658, November/December 1993.					
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EXAMINER		DATE CONSIDERED				

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CITATION	NTI-019-2	09/675,197				
O P E PAYO-1449	APPLICANT Pierrat, et al.					
OCT 1 5 2001 (5)	FILING DATE 9/29/00	GROUP 2812				
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
	Saleh, B. et al., "Reduction Of Errors Of Microphotographic Reproductions By Optimal Corrections Of Original Masks", <i>Optical Engineering</i> , Vo. 20, No. 5, pp. 781-784, September/October 1981.					
Spence, C. et al., "Integration Of Optical Proximity Correction Strategies In Strong Phase Shifters Design For Poly-Gate Layers", <i>Bacus News</i> , Vol. 15, Issue 12, pp. 1, 4-13, December 1999.						
EXAMINER DATE CONSIDERED						

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